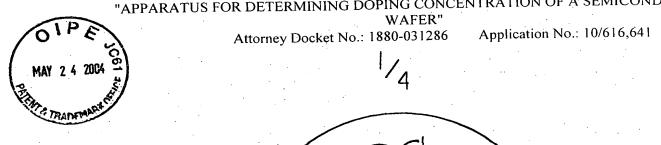
Inventor: William H. Howland
"APPARATUS FOR DETERMINING DOPING CONCENTRATION OF A SEMICONDUCTOR



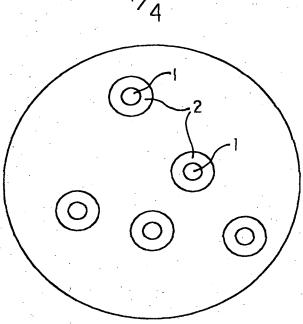
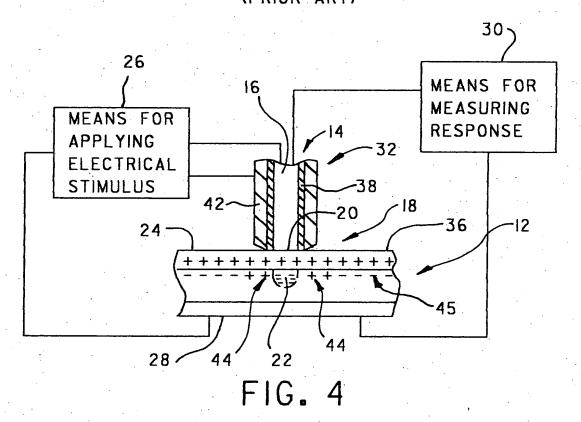


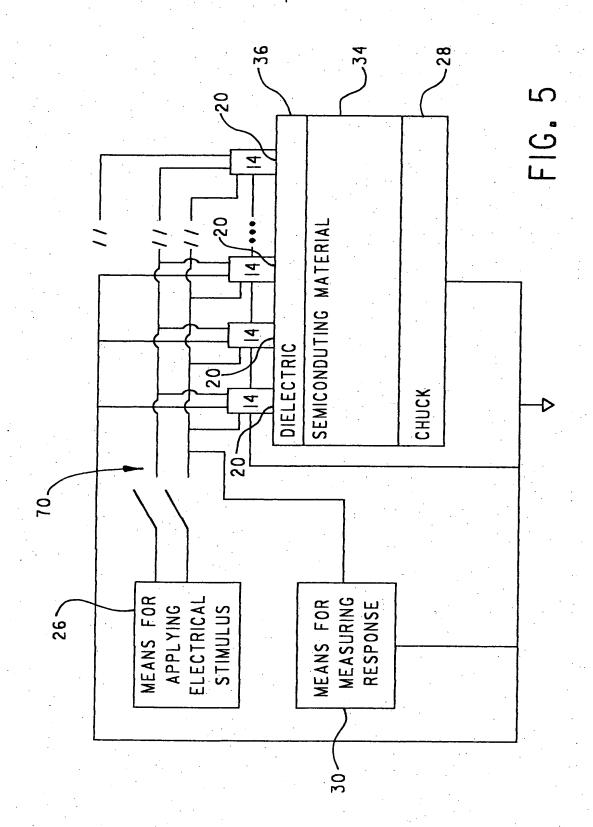
FIG. 1
(PRIOR ART)



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WAFER"

Application No.: 10/616,641 Attorney Docket No.: 1880-031286 MEANS FOR **MEASURING** 26 **RESPONSE** MEANS FOR SHAFT 16 **APPLYING PROBE** ELECTRICAL PROBE GUARD STIMULUS ELEMENT 32 DISTAL END 18. CONDUCTIVE : **TIP 20** SURFACE 24 **OBJECT** CHUCK-**SEMICONDUCTOR** AREA 22 WAFER 12 28 FIG. 2 MEANS FOR **MEASURING** RESPONSE 38 20-32 MEANS FOR 24 -APPLYING ELECTRICAL 34 STIMULUS -26 28 18 FIG. 3

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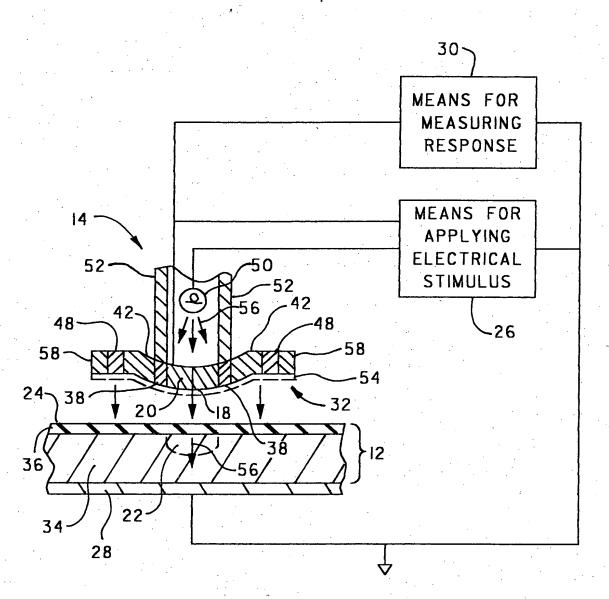


FIG. 6